

ABSTRACT OF THE DISCLOSURE

A method of fabricating micro-electromechanical system (MEMS) structures that can prevent stiction between a microstructure and a substrate or adjacent structures after etching for releasing the microstructure is provided. In a
5 micromaching process for fabricating a microstructure suspended above a substrate using a sacrificial layer, the fabricating method includes stacking an anti-stiction layer, which can be removed by dry etching, before or after stacking a sacrificial layer.